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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q61045

Fumiyoshi ONO

Allowed: February 17, 2004

Appln. No.: 09/672,776 ✓

Group Art Unit: 1765

Confirmation No.: 2256

Examiner: Kin Chan Chen

Filed: September 29, 2000

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND METHOD OF USING SAME

**REQUEST FOR INITIALED AND SIGNED PTO-1449 FORM AND
ACKNOWLEDGEMENT OF RECEIPT OF VERIFIED ENGLISH TRANSLATIONS OF
PROVISIONAL APPLICATIONS**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants hereby respectfully request the Examiner to confirm that the references submitted with Applicants' Information Disclosure Statement filed on September 29, 2000 (copy enclosed with date stamped filing receipt) have been considered by providing Applicants with an initialed and signed copy of the PTO-1449 Form listing these references.

In addition, Applicants hereby respectfully request that the Examiner acknowledge receipt of the verified English translations of provisional application nos. 60/132,426 and 60/102,000 filed on August 26, 1999 and March 16, 1999, respectively, in the provisional application.

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WASHINGTON OFFICE

23373

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Respectfully submitted,

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Date: March 8, 2004



REQUEST OF EARLY NO CATION OF SERIAL NUMBER

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Inventor(s): Fumiyoshi ONO

Title: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR
WAFER AND METHOD OF USING SAME

Atty Doc. #: Q61045 Client: A. AOKI, ISHIDA & ASSOCIATES
Divisional of Appln. No.: 09/313,356

Filing Date: Sept. 29, 2000 # Pgs. Spec/Abst: 16/1 #Claims: 4

Dwg. Sheets: None Decl: Yes Prelim Amdt: No

IDS/Prior Art: Yes Pr Doc: Parent Asgmt: Parent Fee: \$690.00

☒ Check Attached ☐ Charge to Deposit # 19-4880 Atty/Sec:
WAB/KKT/sls

SERIAL NO.:



PATENT APPLICATION
Attorney Docket No.: Q61045

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Fumiyoshi ONO

Divisional of Appln. No. 09/313,356

Group Art Unit: Not yet assigned

Filed: September 29, 2000

Examiner: Not yet assigned

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND
METHOD OF USING SAME

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §§ 1.97 and 1.98

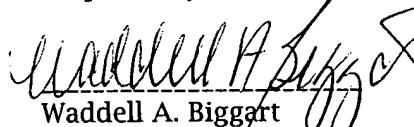
Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In accordance with the duty of disclosure under 37 CFR §1.56, Applicant hereby notifies the U.S. Patent and Trademark Office of the documents which are listed on the attached PTO-1449 form which are all the references of record in parent application No. 09/313,356. Applicant is not submitting duplicate copies of these references but requests that they be listed on the face of any patent granted on the above application. (See 1138 TMOG 39, second column, last paragraph, last sentence.)

The submission of the listed documents is not intended as an admission that any such document constitutes prior art against the claims of the present application. Applicant does not waive any right to take any action that would be appropriate to antedate or otherwise remove any listed document as a competent reference against the claims of the present application.

Respectfully submitted,


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